# Monthly LabAdviser update: 29/7 2016

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| Updated Subject  | Contributor | Link to the updated pages |
| **Lithography – thick CSAR**New section about thick CSAR (AR-P 6200.18) | **Tine Greibe @danchip** | [Lithography/CSAR#CSAR\_6200.18](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/CSAR#CSAR_6200.18) |
| **E-beam lithography**Updated process flow for bilayer stack of LOR5A and CSAR (was send out 23rd of June) | **Tine Greibe @danchip** | [EBeamLithography#E-beam\_resists\_and\_Process\_flow](http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Lithography/EBeamLithography#E-beam_resists_and_Process_flow) |
| **CEN: Nova NanoSEM**Description of Kleindiek micromanipulator and micro 4-point probe to perform resistivity measurements | **Matteo Todeschini @danchip** | [CEN/Nova\_NanoSEM\_600#Kleindiek\_micromanipulator](http://labadviser.danchip.dtu.dk/index.php/LabAdviser/CEN/Nova_NanoSEM_600#Kleindiek_micromanipulator) |

# Equipment Manuals updated in LabManager:

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

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|  | **Manual for Spin Coater: Manual All Purpose** |
|  | **Manual for Spin coater: Manual All Resists** |
|  | **Manual for Spin coater: Manual Standard Resists** |
|  | **Manual for LPCVD Nitride Furnace (4")** |
| http://d4.danchip.dtu.dk/D4Doc/res/menu/user_bullet.gif | **Manual for AOE** |
| http://d4.danchip.dtu.dk/D4Doc/res/menu/user_bullet.gif | **Manual for ASE** |
|  | **Manual for RCA clean of black silicon** |
|  | **Manual for Furnace: Multipurpose Annealing** |
| http://d4.danchip.dtu.dk/D4Doc/res/menu/user_bullet.gif | **Lifetime scanner MDPmap** |
|  | **User manual for E-Beam writer JEOL JBX-9500FS** |

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